



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Chen et al.

Serial No.: 10/032,284

Filed: December 21, 2001

For: Gas Delivery Apparatus and
Method for Atomic Layer
Deposition

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Group Art Unit: Unknown

Examiner: Unknown

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

CERTIFICATE OF MAILING
37 C.F.R. 1.8
I hereby certify that this correspondence is being deposited on
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SECOND PRELIMINARY AMENDMENT

Prior to examination of the above referenced application, Applicants request that the application be amended as follows:

IN THE SPECIFICATION:

Please replace the paragraph [0001] with the following paragraph [0001]:

B' [0001] This application claims benefit of United States provisional Patent Application Serial Number 60/346,086, entitled "METHOD AND APPARATUS FOR ALD DEPOSITION," filed October 26, 2001, which is herein incorporated by reference.